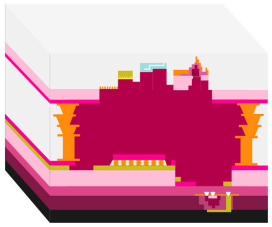
Registration open for: DWL Workshop and Webinar Series

4th DWL Workshop

Sydney 2 Feb 2026



Scan to register for the 4th DWL Workshop, proudly sponsored by the Australian National Fabrication Facility (ANFF).

Join leading researchers, scientists, and micro/nanofabrication experts on Monday, 2 February 2026, at the University of Sydney for a one-day event exploring the latest advancements in direct write lithography (DWL)—including electron, photon, ion beam technologies, and more.

Registration also includes access to a series of educational webinars commencing in November 2025.

Want to present at the workshop?

We're calling on researchers, scientists, and experts in micro and nanofabrication to share their insights at the "Innovative Research in Direct Write Lithography Workshop." For details on how to submit your abstract, scan the QR code on the right or click here.

Workshop keynote speakers

Gerald G. Lopez, Ph.D.
Director of Operations and Business & Center Associate Director Singh Center for Nanotechnology
University of Pennsylvania | MAEBL Co-Founder and Board Chair | EIPBN Operations Trustee

John S. Petersen
Scientific Director of Lithography & co-leader of AttoLab at imec, Professor at University of Maryland

Upcoming webinars

	Melb, Syd	Adelaide	Perth, Singapore	Berlin	NY	LA	Topic / Title	Facilitator / Speaker
W4	AEDT 12:00 29.01.26	ACDT 11:30 29.01.26	AWST / SGT 09:00 29.01.26	CET 2:00 29.01.26	EST 20:00 28.01.26	PST 17:00 28.01.26	Atomic Mechanisms During Plasma Etching	David Graves (Princeton University)
W5	AEDT 11:00 19.02.26	ACDT 10:30 19.02.26	AWST / SGT 8:00 19.02.26	CET 1:00 19.02.26	EST 19:00 18.02.26	PST 16:00 18.02.26	Focused Ion Beams for Nanofabrication: What happens when the ion hits the sample?	Lena Wolff (AXT)
W6	AEDT 11:00 19.03.26	ACDT 10:30 19.03.26	AWST / SGT 8:00 19.03.26	CET 1:00 19.03.26	EDT 20:00 18.03.26	PDT 17:00 18.03.26	Using the right tool for the job: Comparing ALE, RIE and IBE	Nick Chittock (Oxford Instruments Plasma Technology)
W7	AEST 11:00 08.04.26	ACST 10:30 08.04.26	AWST / SGT 9:00 08.04.26	CEST 3:00 08.04.26	EDT 21:00 07.04.26	PDT 18:00 07.04.26	Helicon Double Layer Thruster: A radiofrequency plasma source with many applications	Christine Charles (ANU)
W8	AEST 11:00 30.04.26	ACST 10:30 30.04.26	AWST / SGT 9:00 30.04.26	CEST 3:00 30.04.26	EDT 21:00 29.04.26	PDT 18:00 29.04.26	Plasma etch technology and applications from KLA	David Johnson (KLA)

SCAN TO REGISTER FOR THE EVENT OR CLICK HERE

+ CONTACT

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